

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. 10/671,922
Confirmation No. 8459
Filing Date September 24, 2003
Inventor..... Garo J. Derderian et al.
Assignee Micron Technology, Inc.
Group Art Unit..... 2812
Examiner Gurley, Lynne Ann
Attorney's Docket No. MI22-2296
Title: Atomic Layer Deposition Methods, and Methods of Forming Materials Over Semiconductor Substrates

RESPONSE TO AUGUST 1, 2006 FINAL OFFICE ACTION
TO ACCOMPANY RCE FILING

To: Mail Stop RCE
Commissioner for Patents
P.O. Box 1450
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AMENDMENTS

Introductory Comments

In reply to the Final Office Action of August 1, 2006, applicant amends and remarks as follows.